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L Number	Hits	Search Text	DB	Time stamp
1	1000	((physical and chemical) same etching same plasma	USPAT; US-PGPUB	2002/08/22 15:11
2	534	((physical and chemical) same etching same plasma) and (nitrogen or argon or helium)	USPAT; US-PGPUB	2002/08/22 14:51
3	328	((physical and chemical) same etching same plasma) and (nitrogen or argon or helium)) and (trench or hole or opening or recess)	USPAT; US-PGPUB	2002/08/22 15:11
4	177	((physical and chemical) same etching same plasma) and (nitrogen or argon or helium)) and (trench or hole or opening or recess)) and (organic or polymer)	USPAT; US-PGPUB	2002/08/22 14:52
5	177	((physical and chemical) same etching same plasma) and (nitrogen or argon or helium)) and (trench or hole or opening or recess)) and (organic or polymer)) and (cleaning or removing or etching)	USPAT; US-PGPUB	2002/08/22 14:52
6	173	((physical and chemical) same etching same plasma) and (nitrogen or argon or helium)) and (trench or hole or opening or recess)) and (organic or polymer)) and (cleaning or removing or etching)) and @ad<=20010828	USPAT; US-PGPUB	2002/08/22 14:53
7	98	((physical and chemical) same etching same plasma	EPO; JPO; DERWENT; IBM TDB	2002/08/22 15:11
8	16	((physical and chemical) same etching same plasma) and (trench or hole or opening or recess)	EPO; JPO; DERWENT; IBM TDB	2002/08/22 15:11

review the marked
PA @ 1+2 after 8/3/02

	U	1 [1]	Document ID	Issue Date	Pages
1	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 20020106845 A1	20020808	14
2	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 20020073922 A1	20020620	80
3	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 20020072223 A1	20020613	22
4	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 20020022342 A1	20020221	17
5	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 20020006674 A1	20020117	21
6	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 20010055852 A1	20011227	44
7	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 20010049150 A1	20011206	42
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9	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 20010046780 A1	20011129	26
10	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 20010030169 A1	20011018	15
11	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6432835 B1	20020813	59
12	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6331380 B1	20011218	21
13	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6307213 B1	20011023	9

	Title	Current OR	Current XRef
1	METHOD FOR ROUNDING CORNERS AND REMOVING DAMAGED OUTER SURFACES OF A TRENCH	438/172	
2	CHAMBER LINER FOR HIGH TEMPERATURE PROCESSING CHAMBER	118/715	
3	Method of enhancing adhesion of a conductive barrier layer to an underlying conductive plug and contact for ferroelectric applications	438/629	
4	Method and device for producing a metal/metal contact in a multilayer metallization of an integrated circuit	438/453	
5	Hydrogen-free contact etch for ferroelectric capacitor formation	438/3	438/239; 438/256; 438/597
6	Integrated circuit and method	438/396	
7	Method for etching organic film, method for fabricating semiconductor device and pattern formation method	438/8	
8	Method for etching organic film, method for fabricating semiconductor device and pattern formation method	438/725	438/780
9	Method for etching organic film, method for fabricating semiconductor device and pattern formation method	438/712	
10	Method of etching organic film and method of producing element	216/17	216/41; 216/66
11	Process for fabricating an integrated circuit device having a capacitor with an electrode formed at a high aspect ratio	438/720	438/253; 438/396; 438/722
12	Method of pattern etching a low K dielectric layer	430/318	430/311; 430/313
13	Method for making a fuse structure for improved repaired yields on semiconductor memory devices	257/50	257/529; 257/530

	Retrieval Classif	Inventor	S	C	P	2	3	4	5
1		CHAO, JOHN et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
2		FRANKEL, JONATHAN et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
3		Gilbert, Stephen R. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
4		Schneegans, Manfred et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
5		Ma, Shawming et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
6		Moise, Theodore S. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
7		Nakagawa, Hideo et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
8		Nakagawa, Hideo	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
9		Nakagawa, Hideo	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
10		Kitagawa, Hideo et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
11		Yunogami, Takashi et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
12		Ye, Yan et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
13		Huang, Kuo Ching et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

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14	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6296777 B1	20011002	8
15	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6287961 B1	20010911	19
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18	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6180533 B1	20010130	22
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21	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6080529 A	20000627	21
22	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6004884 A	19991221	13
23	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 6004883 A	19991221	13
24	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5980768 A	19991109	12

	Title	Current OR	Current XRef
14	Structuring process	216/40	216/47; 216/49; 216/51; 216/67; 216/72; 216/76; 216/77; 216/78; 216/79
15	Dual damascene patterned conductor layer formation method without etch stop layer	438/638	438/637; 438/783; 438/924
16	Mechanism for bow reduction and critical dimension control in etching silicon dioxide using hydrogen-containing additive gases in fluorocarbon gas chemistry	216/79	438/710
17	Integrated circuit and method	438/396	
18	Method for etching a trench having rounded top corners in a silicon substrate	438/714	438/719; 438/724; 438/739
19	Method for making a fuse structure for improved repaired yields on semiconductor memory devices	438/132	438/601; 438/648; 438/662; 438/685
20	Prevention of photoresist poisoning from dielectric antireflective coating in semiconductor fabrication	430/317	430/314; 430/316
21	Method of etching patterned layers useful as masking during subsequent etching or for damascene structures	430/318	430/311; 430/313
22	Methods and apparatus for etching semiconductor wafers	438/714	216/72; 438/738; 438/742; 438/952
23	Dual damascene patterned conductor layer formation method without etch stop layer	438/706	438/711; 438/723
24	Methods and apparatus for removing photoresist mask defects in a plasma reactor	216/67	216/72; 438/710

	Retrieval Classif	Inventor	S	C	P	2	3	4	5
14		Engelhardt, Manfred et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
15		Liu, Chung-Shi et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
16		Hills, Graham et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
17		Moise, Theodore S. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
18		Jain, Alok et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
19		Huang, Kuo Ching et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
20		Tobben, Dirk et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
21		Ye, Yan et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
22		Abraham, Susan C.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
23		Yu, Chen-Hua Douglas et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
24		Abraham, Susan C.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

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26	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5925577 A	19990720	13
27	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5895239 A	19990420	21
28	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5893734 A	19990413	19
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33	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5545290 A	19960813	8
34	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5213659 A	19930525	6
35	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 5157000 A	19921020	6

	Title	Current OR	Current XRef
25	Low pressure and low power Cl.sub.2 /HCl process for sub-micron metal etching	438/714	204/192.35; 438/696; 438/720
26	Method for forming via contact hole in a semiconductor device	438/725	134/1.1; 134/1.2; 134/1.3; 216/17; 438/637; 438/639; 438/669; 438/704; 438/720; 438/963
27	Method for fabricating dynamic random access memory (DRAM) by simultaneous formation of tungsten bit lines and tungsten landing plug contacts	438/239	438/254
28	Method for fabricating capacitor-under-bit line (CUB) dynamic random access memory (DRAM) using tungsten landing plug contacts	438/239	438/254
29	Method for dry etching sidewall polymer	134/1.2	438/696; 438/723; 438/725; 438/734; 438/740
30	Method of plasma etching	438/738	216/77; 438/721; 438/742
31	Mechanism for uniform etching by minimizing effects of etch rate loading	216/72	216/67; 438/714; 438/740
32	Process for forming multilayer wiring	438/641	438/675; 438/677
33	Etching method	438/695	216/37; 216/58; 216/64; 438/696
34	Combination usage of noble gases for dry etching semiconductor wafers	216/48	216/66; 216/79
35	Method for dry etching openings in integrated circuit layers	438/704	148/DIG.51; 427/576

	Retrieval Classif	Inventor	S	C	P	2	3	4	5
25		Naeem, Munir D. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
26		Solis, Ramiro	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
27		Jeng, Erik S. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
28		Jeng, Erik S. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
29		Solis, Ramiro	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
30		Yanagawa, Shusaku	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
31		Abraham, Susan C.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
32		Nishitani, Eisuke et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
33		Douglas, Monte A.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
34		Blalock, Guy T. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
35		Elkind, Jerome L. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

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33	US 5545290	<input type="checkbox"/>
34	US 5213659	<input type="checkbox"/>
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36	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 4529860 A	19850716	8
37	<input type="checkbox"/>	<input checked="" type="checkbox"/>	US 4376672 A	19830315	15

	Title	Curr nt OR	Current XRef
36	Plasma etching of organic materials	219/121.41	216/58; 216/67; 219/121.42; 219/121.43; 430/313; 430/323; 430/330
37	Materials and methods for plasma etching of oxides and nitrides of silicon	438/713	148/DIG.131; 204/192.32; 204/298.31; 252/79.1; 430/313; 430/317; 438/723; 438/724

	Retrieval Classif	Inventor	S	C	P	2	3	4	5
36		Robb, Francine Y.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>
37		Wang, David N. et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>

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